FORM PTO-1449 . U.S. DEPARTMENT OF COMMERCE ATTY. DOCKET NO. SERIAL NO. BA-22772 APPLICANT LIST OF PRIOR ART CITED BY APPLICANT YEAN-KUEN FANG, Et Al (Use several sheets if necessary) FILING DATE U.S. PATENT DOCUMENTS EXAMINER FILING DATE

IF APPROPRIATE SUBCLASS CLASS DOCUMENT NUMBER NAME DATE AA 10 4 09003/21/00 Chen 356 35.5 4 2 7 1 7 4/17/84 AB 766 73 Kurtz et al AC 0 4 4 7 0 5 4 /04 /00 Neukermans et al 73 504.02 AD AE AF AG AH AI AJ AK FOREIGN PATENT DOCUMENTS TRANSLATION COUNTRY CLASS SUBCLASS DOCUMENT NUMBER DATE YES AL AM AN AO OTHER PRIOR ART (Including Author, Title, Date, Perlinent Pages, Etc.) M. Zhang, et al, "Frictional Action at Lôwer Limb/Prosthetic AR Socket Interface", Med. Eng. Phy. Vol. 18, No. 3, pp 207-214,1996 M. Zhang, Arthur F.T. Mak, "A Finite Element Analysis of the Load, AS etc.", IEEE Transactions on Rehab, Eng., Vol.4,No.4,pp337-346,1996 Jyh-Jier Ho, et al, "Development of a Micro-Electro-Mechanical AT System Pressure Sensor for Rehabilitation Engineering Applications", International J. of Electronics, Vol. 87. No. 6,pp757-767. (2000) DATE CONSIDERED EXAMINER \*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not

In conformance and not considered. Include copy of this form with next communication to applicant.

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE. ATTY. DOCKET NO. FORM PTO-1449 ... BA-22772 APPLICANT LIST OF PRIOR ART CITED BY APPLICANT YEAN-KUEN FANG. Et Al (Us several sheets if necessary) FILING DATE U.S. PATENT DOCUMENTS EXAMINER FILING DATE CLASS SUBCLASS DOCUMENT NUMBER DATE NAME INITIAL AA AB AC AD AE AF AG AH AJ FOREIGN PATENT DOCUMENTS TRANSLATION SUBCLASS CLASS DOCUMENT NUMBER DATE COUNTRY AL AM AN AO OTHER PRIOR ART (Including Author, Title, Date, Perlinent Pages, Etc.) Chang Liu, et al, "A Micromachined Flow Shear-Stress Sensor Based on Thermal Transfer Principles", J. of MEMS, Vol. 8, No. 1, pp90-99, 1999 Tao Pan, et al/"Microfabricated Shear Stress Sensors, Part 1: Design and Fabrication", AIAA J., Vol.37, No. 1, pp66-72, 1999 Javad Shajii, et al, "A Micromachined Floating-Element Shear Stress Sensor Using Wafer-Bonding Technoloty", J. of MEMS, Vol.1, No.2, pp89DATE CONSIDERED 8/2013 94,1992

EXAMINER

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not In conformance and not considered. Include copy of this form with next communication to applicant.

									_								Sheel3_		<u> </u>
PTO-1449 U.S. DEPARTMO OF COMMERCE PATENT AND TRADEMARK OFFICE								FICE	BA-	CKET 1		•	SERI	AL NO.					
LIST OF PRIOR ART CITED BY APPLICANT (Use several sheets if necessary)									APPLI essary)	CANT		APPLICANT YEAN-KUEN FANG, Et Al FILING DATE GROUP							
	•-															L			
										U.S. PA	TENT	DOCUMEN.	rs			<b></b> -	<del></del>		
INER		DOG	LUM	ENT NUMBER			DAT	rŒ			NAME			CLASS	รบ	SUBCLASS	IF APPR	DATE OPRIATE	
	AA												<del></del>						
	AB																		
	AC			$\perp$			1									-			
	AD					_						<del></del>							
	AE	_			$\perp$	1	_		<del></del> .	·	·····		<del></del>		<b></b>				
<u></u>	AF	_			4	4-	-	-			<del></del>				-			-	
	AG	_	$\perp$		+	1	+	<u> </u>				· · · · · · · · · · · · · · · · · · ·	<del></del>						
	HA	$\vdash$	+	H		+	+	╂-		<del>                                     </del>									
	AI	+	+		H	+	+	-		1,									
	AK	+	+		H	1	$\dashv$	-			<del></del>								
		1								FORFIG	N PAT	ENT DOCU	MENT	S	_1				
<del></del>	T	T		CUMENT NUMBER			, ,	T			OUNTRY			CLA	ss	SUBCLAS	S TRANS	HO	
<u></u>	AI	+	1	Τ	П			+	<del></del>								<u> </u>		
	A	4	+	T				T								<del></del>			<del></del>
	Al	N	1	$\dagger$	1			T									-		_
<del></del>	A	0	1	+	1									<u></u> :	1			_	-
•	^	Р											Data 1	Pertinent	Pages. I	ic.)			
										RY (Includ									
4	1	x		A. Padmanabhan, et. al. "Micromachined sensors for static and dynam															
′ /′	<b>`</b>   "		ŀ	'shear-stress measurement in aerodynamic flows," Transducers' 97,															
n	1,	\s -	1	pp. 137-140. 1997															
	-	+	-	·															
	4	AT	-					<u> </u>											
XVM	NER			L				1	-		<del></del>	DATE	CONS	DERED	81.2	ij	]		
		. /			24.5		1.		-		-	1	•						

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.